Form 1449 (Modified) Atty Docket No. Serial No.: MAT-12CIP Not Yet Assigned **Information Disclosure** Applicants: 10/803528 **Statement By Applicant** Neil M. Mackie et al Filing Date Group 1763 (Use Several Sheets if Necessary) March 17, 2004 Not Yet Assigned

U.S. Patent Documents

Examiner						Sub-	Filing
Initial	No.	Patent No.	Date	Patentee	Class	class	Date
MGA	A	4,058,430	11/15/77	Suntola et al			
	В	4,413,022	11/1/83	Suntola et al			
	С	4,798,165	1/17/89	deBoer et al			
	D	5,006,363	4/9/91	Fujii et al			
	E	5,294,568	3/15/94	McNeilly et al			
	F	5,493,987	2/27/96	McDiarmid et al			
	G	5,648,321	7/15/97	Bednorz et al		7	
	_H	5,773,078	6/30/98	Skelly			
	I	5,786,248	7/28/98	Schuegraf			
	J	5,830,277	11/3/98	Johnsgard et al			
	K	5,856,242	1/5/99	Arai et al			
	L	5,916,365	6/29/99	Sherman		1	
	M	5,964,949	10/12/99	Savas		<u> </u>	<u> </u>
	N	5,968,279	10/19/99	MacLeish et al			
	0	5,972,430	10/26/99	Dimeo Jr et al			
	P	6,013,553	1/11/00	Wallace et al		<u> </u>	
	Q	6,015,590	1/18/00	Suntola et al			
	R	6,037,235	3/14/00	Narwankar et al			
	S	6,118,100	9/12/00	Mailho et al			
	Т	6,133,550	10/17/00	Griffiths et al			
	Ū	6,136,725	10/24/00	Loan et al			
	V	6,150,209	11/21/00	Sun et al			
	w	6,174,809	1/16/01	Kang et al			
	X	6,177,341	1/23/01	Lai			
	Y	6,198,074	3/6/01	Savas			
	Z	6,200,634	3/13/01	Johnsgard et al			
	AA	6,203,613	3/20/01	Gates et al			
	BB	6,207,583	3/27/01	Dunne et al			
	CC	6,301,434	10/9/01	McDiarmid et al			
	DD	6,303,520	10/16/01	Kwong et al			
	EE	6,303,524	10/16/01	Sharangpani et al		- 	
	FF	6,331,697	12/18/01	Savas			
	GG	6,342,691	1/29/02	Johnsgard et al			
	НН	6,342,777	1/29/02	Takahashi			
1	II	6,355,909	3/12/02	Griffiths et al			
	JJ	6,420,279	7/16/02	Ono et al	 		
1	KK	6,436,796	8/20/02	Mailho et al			
	LL	6,449,428	9/10/02	Aschner et al			
1	MM	6,451,713	9/17/02	Tay et al			
1,	NN	6,531,793	2/13/03	Chang et al			
A	00	6,540,838	4/1/03	Sneh et al			

Foreign Patent or Published Foreign Patent Application

Examiner		Document	Publication	Country or		Sub-	Transla	tion
Initial	No.	No.	Date	Patent Office	Class	class	Yes	No
	- PP							

Other Documents

no copy

Examiner				
Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication		
	QQ	D. Park et al. SiON/Ta2O5/TiN Gate Stack Transistor with 1.8nm Equivalent SiO2 Thickness, 1998.		
		Tech Dig Int Electron Device Meet, P 381		
MGA	RR	Laun et al, Ultra Thin High Quality Ta2O5 Gate Dielectric Prepared By In Situ Rapid Thermal Processing, 1999, Tech Dig Int Electron Device Meet, 4 Pages		
MGA	SS	Wilk et al, Hafnium and Zirconium Silicates for Advanced Gate Dielectrics, 2000, Journal of Applied Physics, Vol 87(1), pp 484-492		
MGA	TT	Wilk et al, Stable Zirconium Silicate Gate Dielectrics Deposited Directly on Silicon, 1999, Applied Physics Letters, 76(1), pp 112-114		
MGA	UU	Denis et al, Model to Simulate Parabolic Followed by Linear Oxidation Kinetics, 1988, Oxideation of Metals, pp 153-167		
MGA	VV	Schuisky et al, Atomic Layer Chemical Vapor Deposition of TiO2 Low Temperature Epitaxy of Rutile and Anatase, 2000, Journal of The Electrochemical Society, Vol 147(9), pp 3319-3325		
MGA	ww			
MGA	XX	Buchan et al, Epitaxial Growth of GaAs with (C2H%)2GaCl and AsH3 in a Hot-Wall System, 1991, Journal of Crystal Growth 107, pp 331-336		
MGA	YY	Higashi et al, Sequential Surface Chemical Reaction Limited Growth of High Quality Al2O3 dielectrics		
Examiner		Date Considered		
/Ma	ureen	Arancibia/ 01/19/2007		
C	:41 - 1 - ta - 4	ion considered. Describing the section is a section of the section		

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.